

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination NAFTALI ET AL.	
		Examiner KARL I.E. TAMAI	Art Unit 2834	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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**NON-PATENT DOCUMENTS**

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
U	Xie et al., A CMOS-MEMS Micromirror with Large Out-of-Plane Actuation", 2001 ASME International Mechanical Engineering congress and Exposition, November 11-16, 2001, NY, NY, MEMS-VOL3, IMECE2001/MEMS23813
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